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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/734,812	12/11/2003	Peter A. Jardine	P/4242-6	2786
2352	7590	03/09/2005		EXAMINER
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			ART UNIT	PAPER NUMBER
			1775	

DATE MAILED: 03/09/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary	Application No.	Applicant(s)	
	10/734,812	JARDINE, PETER A.	
	Examiner	Art Unit	
	John J. Zimmerman	1775	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) Responsive to communication(s) filed on 09 December 2004.
- 2a) This action is FINAL. 2b) This action is non-final.
- 3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) Claim(s) 1-20 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) Claim(s) _____ is/are allowed.
- 6) Claim(s) 1-20 is/are rejected.
- 7) Claim(s) _____ is/are objected to.
- 8) Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) The specification is objected to by the Examiner.
- 10) The drawing(s) filed on _____ is/are: a) accepted or b) objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) All b) Some * c) None of:
1. Certified copies of the priority documents have been received.
 2. Certified copies of the priority documents have been received in Application No. _____.
 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|---|---|
| 1) <input type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. _____. |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date _____. | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| | 6) <input type="checkbox"/> Other: _____. |

SECOND OFFICE ACTION

Amendments

1. This Second Office Action is in response to the Amendment and Response and the Affidavit under Rule 1.131 and 1.132 in Support of U.S. Appl. Ser. No. 10/734,812 of Peter Jardine received December 9, 2004.

Double Patenting

2. The nonstatutory double patenting rejection is based on a judicially created doctrine grounded in public policy (a policy reflected in the statute) so as to prevent the unjustified or improper timewise extension of the "right to exclude" granted by a patent and to prevent possible harassment by multiple assignees. See *In re Goodman*, 11 F.3d 1046, 29 USPQ2d 2010 (Fed. Cir. 1993); *In re Longi*, 759 F.2d 887, 225 USPQ 645 (Fed. Cir. 1985); *In re Van Ornum*, 686 F.2d 937, 214 USPQ 761 (CCPA 1982); *In re Vogel*, 422 F.2d 438, 164 USPQ 619 (CCPA 1970); and, *In re Thorington*, 418 F.2d 528, 163 USPQ 644 (CCPA 1969).

A timely filed terminal disclaimer in compliance with 37 CFR 1.321(c) may be used to overcome an actual or provisional rejection based on a nonstatutory double patenting ground provided the conflicting application or patent is shown to be commonly owned with this application. See 37 CFR 1.130(b).

Effective January 1, 1994, a registered attorney or agent of record may sign a terminal disclaimer. A terminal disclaimer signed by the assignee must fully comply with 37 CFR 3.73(b).

3. Claims 15-16 and 18 are rejected under the judicially created doctrine of obviousness-type double patenting as being unpatentable over claims 9-10 of U.S. Patent No. 6,689,486. Although the conflicting claims are not identical, they are not patentably distinct from each other because the coverage of the claims of the pending application encompass the nickel and titanium

materials required in the claims of the patent. Since shape memory alloys comprising nickel and titanium are among the most common shape memory alloys available, nickel and titanium memory alloys are clearly obvious materials to use for pending claims 15-18. In addition, as evidenced by claim 10 of the patent, three-dimensional shapes for the actuator are clearly covered by the claims of the patent. In addition, the intended use "for active flow control" of the claims of the patent do not add any physical limitations that would not be present in claims 15-18 of this pending application. Regarding the limitations of claims 16-18 of the pending application, these embodiments fall within the scope of the claims of the patent and in view of the fact that the claims of the patent recite use as an actuator and any shape capable of movement could function as an actuator. Thus, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use any of the myriad of possible actuator shapes for the actuator shape of the patent's claims and still fall within the coverage of the patented claims.

Claim Rejections - 35 USC § 112

4. The following is a quotation of the first paragraph of 35 U.S.C. 112:

The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.

5. Claims 1-20 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the enablement requirement. The claims contains subject matter which was not described in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention. In addition, the specification does

not enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to practice the invention commensurate in scope with these claims. The Jardine affidavit, received December 9, 2004, states:

By multiplying the multitude of different compositions and the variety of different percentages of each component metal, the number of shape memory alloy compositions to try becomes infinite. Furthermore, as stated in the specification, processing conditions, such as specific ranges of target temperature, processing temperatures of the wafer, and vacuum pressures during sputter deposition are needed to make two-way shape memory effect devices. Thus, even if it is obvious to try other shape memory alloys, besides Ni:Ti, the infinite variety of shape memory alloys, percentages of component metal, and combinations of processing conditions requires undue experimentation by a routiner in the art. As the references that teach two-way shape memory devices are limited only to Ni:Ti, and alloys thereof, as an operable system, a person of ordinary skill in the art would not have sufficient expectations of success in developing new two-way shape memory effect processes with new alloys without undue experimentation. In addition, the equipment required to prepare a Ni:Ti thin-film, two-way shape memory device is very expensive and must be substantially customized to allow for controlling the important processing conditions. Furthermore, each experiment is a complicated and time-consuming task that takes laboratory time and talented technicians to prepare the targets, substrates and high vacuum chamber, sputter deposit the device under the correct processing conditions, further processing of the sample to etch at least a portion of the thin film from the substrate, preparing a method of heating the thin film or activating the shape memory effect in some other manner, and verifying that shape memory effect, if any, is repeatable and useful. Thus, undue experimentation would be necessary to determine the specific shape memory alloys and processing conditions disclosed and claimed in the above-referenced application.

Furthermore, each new alloy system requires the use of a different combination of target temperature, processing temperature of the wafer, distance from the target to the wafer and vacuum pressure ranges during processing in order to successfully manufacture two-way shape memory alloy devices, requiring months of work. This depends not only on the base alloy, but also on the element or elements chosen for X in ternary and higher order alloys, greatly increasing the complexity. Development of new shape memory alloys for two-way shape memory effect devices requires tireless effort and experimentation to synthesize and characterize materials in the correct processing range to produce practical two-way shape memory effect devices. Ternary and higher order alloys require even more work in selecting the compositional ranges for the higher order elements.

The nearly limitless choice of alloys, chemistries and processing conditions makes selection of the right alloy constituents and process variables an exceedingly difficult task for even an expert in the field, which has necessitated research, including experimentation and calculations, to determine the desired ranges of the various processing variables.

The examiner notes that the majority of the pending claims in this application are simply drawn to any shape "memory alloy other than a Ni:Ti-based alloy". It appears clear from the Jardine affidavit that claims of this breadth cannot be enabled since multiplying the multitude of different compositions and the variety of different percentages of each component metal, the number of shape memory alloy compositions to try becomes infinite and requires undue experimentation in order to determine the specific shape memory alloys and processing conditions. From the Jardine affidavit it appears clear that without disclosure of particular two-way shape memory compositions and the specific processing conditions that are appropriate to those particular compositions, there would be no enablement without undue experimentation. A review of the applicant's disclosure, however, shows that the applicant's disclosure fails to disclose processing conditions for two-way shape memory compositions of the claimed breadth. Indeed, judging from the Jardine affidavit standard, the applicant's disclosure appears to fail to show processing conditions sufficient to enable any two-way shape memory effect compositions other than Ni:Ti systems. Applicant's specification simply supplies long lists of elements (e.g. see paragraphs [0069]-[0070]) that might be used in forming two-way shape memory alloys. No processing conditions or even specific alloy composition ratios are supplied. The Jardine affidavit clearly establishes that disclosures of shape memory alloys in this manner are not enabled. In view of the above, the pending claims are not enabled by the disclosure.

Claim Rejections - 35 USC § 102

6. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(a) the invention was known or used by others in this country, or patented or described in a printed publication in this or a foreign country, before the invention thereof by the applicant for a patent.

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

(e) the invention was described in a patent granted on an application for patent by another filed in the United States before the invention thereof by the applicant for patent, or on an international application by another who has fulfilled the requirements of paragraphs (1), (2), and (4) of section 371(c) of this title before the invention thereof by the applicant for patent.

The changes made to 35 U.S.C. 102(e) by the American Inventors Protection Act of 1999 (AIPA) and the Intellectual Property and High Technology Technical Amendments Act of 2002 do not apply when the reference is a U.S. patent resulting directly or indirectly from an international application filed before November 29, 2000. Therefore, the prior art date of the reference is determined under 35 U.S.C. 102(e) prior to the amendment by the AIPA (pre-AIPA 35 U.S.C. 102(e)).

7. Claims 12-15 and 19 are rejected under 35 U.S.C. 102(e) as being anticipated by Hill (U.S. Patent 6,775,046).

8. Hill discloses forming two-way shape memory alloy films in which the film can be made while varying the alloy temperature during sputtering so that the deposited article has a compositional gradient (e.g. see column 4, lines 36-49; column 6, line 47 - column 7, line 35). Hill discloses that alloys of titanium and nickel can be used, but also discloses that other shape

memory alloys such as gold-copper may be used (e.g. see column 2, lines 32-49). Regarding claims reciting and "actuator", the film of Hill has all the structural requirement to be an "actuator". Regarding claims reciting a three-dimensional shape, the shapes of Hill may be three-dimensional (e.g. see paragraph spanning columns 10 and 11).

Claim Rejections - 35 USC § 103

9. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

10. Claims 1-16 and 18-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ho (U.S. Publication No. 2002/0043456) in view of Hill (U.S. Patent 6,775,046) and further in view of Bement (U.S. Publication 2002/0114108).

11. Ho (different inventive entity and published more than one year prior to the filing date of this pending application) discloses forming two-way shape memory alloy films in which the film can be made while varying the target alloy temperature during sputtering so that the deposited article has a compositional gradient (e.g. see claims 1-2). Ho also discloses processing parameters (e.g. vacuum pressure, use of argon) for sputtering two-way shape memory alloy films (e.g. see paragraphs [0059]-[0060]; Tables I-V) and how they affect the final product. Ho discloses that different three-dimensional actuator shapes can be made (e.g. paragraph [0080];

Figure 33). Although Ho may not disclose all the possible shapes that an actuator may have, it would have been obvious to one of ordinary skill in the art at the time the invention was made that any actuator shape could be made by Ho's process. Regarding claims reciting a removable scaffold structure, the substrate upon which the film of Ho is sputtered qualifies as such a structure. Ho may differ from the pending claims in that Ho may not disclose that shape memory alloys other than titanium-nickel alloys can be used for his compositionally graded sputtered two-way shape memory films. Hill, however, discloses that it was known in the art at the time this application was filed that both titanium-nickel shape memory alloys and shape memory alloys of other compositions than titanium-nickel (e.g. gold-copper, column 2, lines 32-49) could be used in the manufacture of compositionally graded sputtered two-way shape memory films (e.g. see column 4, lines 13-49). In view of Hill, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use other conventionally used and known shape memory alloys for the actuators of Ho because Hill clearly shows that non-titanium-nickel alloys would work in Ho's process. Ho and Hill discloses various shape memory alloy compositions in the art, but do not specifically mention the claimed gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum compositions. Bement is cited simply to show that gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum shape memory alloy compositions are conventional shape memory alloy compositions in the art and also that it is well understood in the art that these alloys can be formed by sputtering processes (e.g. see paragraph [0026]). In view of Bement, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum shape memory alloy compositions in Ho's process because Hill clearly shows that

non-titanium-nickel alloys would work in Ho's process and Bement shows these shape memory alloy compositions are conventional in the art. In view of Ho's disclosure of the processing parameters involved in sputtering two-way shape memory alloy films, it would have been obvious to one of ordinary skill in the art at the time the invention was made to optimize the sputtering process parameters for best results for each particular chosen composition.

12. Claims 1-16 and 18-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ho (Sputter Deposition of NiTi Thin Film Exhibiting the SME at Room Temperatures, Proceedings of the Symposium 1998 ASME International Mechanical Engineering Congress and Exposition, Nashville TN, November 14-19, 1999) in view of Hill (U.S. Patent 6,775,046) and further in view of Bement (U.S. Publication 2002/0114108).

13. Ho (different inventive entity and published more than one year prior to the filing date of this pending application) discloses forming two-way shape memory alloy films in which the film can be made while varying the target alloy temperature during sputtering so that the deposited article has a compositional gradient (e.g. see abstract). Ho also discloses processing parameters (e.g. vacuum pressure, use of argon) for sputtering two-way shape memory alloy films (e.g. see entire document and figures) and how they affect the final product. Ho discloses that different three-dimensional actuator shapes can be made (e.g. see Figure 14). Although Ho may not disclose all the possible shapes that an actuator may have, it would have been obvious to one of ordinary skill in the art at the time the invention was made that any actuator shape could be made by Ho's process. Regarding claims reciting a removable scaffold structure, the substrate upon

Art Unit: 1775

which the film of Ho is sputtered qualifies as such a structure. Ho may differ from the pending claims in that Ho may not disclose that shape memory alloys other than titanium-nickel alloys can be used for his compositionally graded sputtered two-way shape memory films. Hill, however, discloses that it was known in the art at the time this application was filed that both titanium-nickel shape memory alloys and shape memory alloys of other compositions than titanium-nickel (e.g. gold-copper, column 2, lines 32-49) could be used in the manufacture of compositionally graded sputtered two-way shape memory films (e.g. see column 4, lines 13-49). In view of Hill, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use other conventionally used and known shape memory alloys for the actuators of Ho because Hill clearly shows that non-titanium-nickel alloys would work in Ho's process. Ho and Hill discloses various shape memory alloy compositions in the art, but do not specifically mention the claimed gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum compositions. Bement is cited simply to show that gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum shape memory alloy compositions are conventional shape memory alloy compositions in the art and also that it is well understood in the art that these alloys can be formed by sputtering processes (e.g. see paragraph [0026]). In view of Bement, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum shape memory alloy compositions in Ho's process because Hill clearly shows that non-titanium-nickel alloys would work in Ho's process and Bement shows these shape memory alloy compositions are conventional in the art. In view of Ho's disclosure of the processing parameters involved in sputtering two-way shape memory alloy films, it would have been obvious to one of ordinary

skill in the art at the time the invention was made to optimize the sputtering process parameters for best results for each particular chosen composition.

14. Claims 1-16 and 18-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ho (Sputter Deposition of NiTi Thin Film Shape Memory Alloy Using a Heated Target, Thin Solid Films 370, July 17, 2000, pp. 18-29) in view of Hill (U.S. Patent 6,775,046) and further in view of Bement (U.S. Publication 2002/0114108).

15. Ho (different inventive entity and published more than one year prior to the filing date of this pending application) discloses forming two-way shape memory alloy films in which the film can be made while varying the target alloy temperature during sputtering so that the deposited article has a compositional gradient (e.g. see abstract). Ho also discloses processing parameters (e.g. vacuum pressure, use of argon) for sputtering two-way shape memory alloy films (e.g. entire article) and how they affect the final product. Although Ho may not disclose all the possible shapes that the films may have, it would have been obvious to one of ordinary skill in the art at the time the invention was made that any functional shape memory configuration could be made by Ho's process. Regarding claims reciting a removable scaffold structure, the substrate upon which the film of Ho is sputtered qualifies as such a structure. Ho may differ from the pending claims in that Ho may not disclose that shape memory alloys other than titanium-nickel alloys can be used for his compositionally graded sputtered two-way shape memory films. Hill, however, discloses that it was known in the art at the time this application was filed that both titanium-nickel shape memory alloys and shape memory alloys of other compositions than

titanium-nickel (e.g. gold-copper, column 2, lines 32-49) could be used in the manufacture of compositionally graded sputtered two-way shape memory films (e.g. see column 4, lines 13-49). In view of Hill, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use other conventionally used and known shape memory alloys for the actuators of Ho because Hill clearly shows that non-titanium-nickel alloys would work in Ho's process. Ho and Hill discloses various shape memory alloy compositions in the art, but do not specifically mention the claimed gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum compositions. Bement is cited simply to show that gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum shape memory alloy compositions are conventional shape memory alloy compositions in the art and also that it is well understood in the art that these alloys can be formed by sputtering processes (e.g. see paragraph [0026]). In view of Bement, it would have been obvious to one of ordinary skill in the art at the time the invention was made to use gold-cadmium, copper-zinc-aluminum and copper-nickel-aluminum shape memory alloy compositions in Ho's process because Hill clearly shows that non-titanium-nickel alloys would work in Ho's process and Bement shows these shape memory alloy compositions are conventional in the art. In view of Ho's disclosure of the processing parameters involved in sputtering two-way shape memory alloy films, it would have been obvious to one of ordinary skill in the art at the time the invention was made to optimize the sputtering process parameters for best results for each particular chosen composition.

Allowable Subject Matter

16. Claim 17 was previously indicated as allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims. In view of the rejection under 35 U.S.C. 112, first paragraph, this indication of allowability is withdrawn.

Response to Arguments

17. Applicant's arguments filed December 9, 2004 have been fully considered but they are not persuasive.

18. Regarding the rejection of claims 15-16 and 18 under the judicially created doctrine of obviousness-type double patenting as being unpatentable over claims 9-10 of U.S. Patent No. 6,689,486, applicant argues that the bubble membrane claimed in the patent is not produced by use of a three-dimensional thin film, but is rather is created from a planar sheet of thin film. Applicant's argument is not persuasive because the rejected claims do not distinguish between a film formed on a three-dimensional scaffold and a film formed as a planar film that is then distorted out of plane. The pending claims only require a three-dimensional shape. Applicant's arguments addressing how the films are formed are not commensurate with the claim limitations.

19. Regarding the rejection of claims 12-15 and 19 under 35 U.S.C. 102(e) as being anticipated by Hill (U.S. Patent 6,775,046), applicant argues that Hill lacks support for non-titanium films. The examiner does not find this argument convincing since the rejected claims

are not drawn to non-titanium films. Arguments which are not commensurate with the limitations of the rejected claims are not convincing.

20. The pending claims have been rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the enablement requirement. The claims contains subject matter which was not described in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention. In addition, the specification does not enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to practice the invention commensurate in scope with these claims. The examiner notes that the majority of the pending claims in this application are simply drawn to any shape "memory alloy other than a Ni:Ti-based alloy" and it appears clear from the Jardine affidavit that claims of this breadth are not enabled since multiplying the multitude of different compositions and the variety of different percentages of each component metal, the number of shape memory alloy compositions to try becomes infinite and requires undue experimentation in order to determine the specific shape memory alloys and processing conditions. From the Jardine affidavit it appears clear that without disclosure of particular two-way shape memory compositions and the specific processing conditions that are appropriate to those particular compositions, there would be no enablement without undue experimentation. A review of the applicant's disclosure clearly shows that the applicant's disclosure fails to disclose processing conditions for two-way shape memory compositions of the claimed breadth. Indeed, judging from the Jardine affidavit's standard, the applicant's disclosure appears to fail to show processing conditions sufficient to enable any two-way shape memory effect compositions other than Ni:Ti

systems. Applicant's specification simply supplies long lists of elements (e.g. see paragraphs [0069]-[0070]) that might be used in forming two-way shape memory alloys. No processing conditions or even specific alloy composition ratios are supplied. The Jardine affidavit clearly establishes that disclosures of shape memory alloys in this manner are not enabled.

21. Regarding the rejection of claims 1-16 and 18-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ho (U.S. Publication No. 2002/0043456 and Sputter Deposition of NiTi Thin Film Shape Memory Alloy Using a Heated Target, Thin Solid Films 370, July 17, 2000, pp. 18-29) in view of Hill (U.S. Patent 6,775,046) and further in view of Bement (U.S. Publication 2002/0114108), the Jardine affidavit states that "it is my opinion that Au:Cu is not amenable to the two-way shape memory effect, using any process that varies the temperature of the target". This argument is not convincing since no factual evidence was presented to support the "opinion".

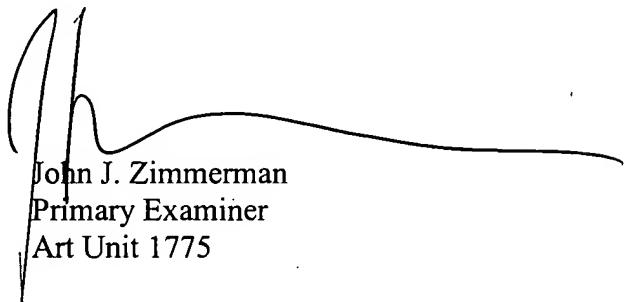
Conclusion

22. In view of the new rejection of claims 1-20 based on 35 U.S.C. 112, first paragraph, this Second Office Action has not been made Final. This rejection was based on the conclusions of the Jardine affidavit and applicant's arguments submitted December 9, 2004.

23. Any inquiry concerning this communication or earlier communications from the examiner should be directed to John J. Zimmerman whose telephone number is (571) 272-1547. The examiner can normally be reached on 8:30am-5:00pm, M-F. Supervisor Deborah Jones can

be reached on (571) 272-1535. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

24. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).



John J. Zimmerman
Primary Examiner
Art Unit 1775

jjz
March 3, 2005